

# Multi-chamber Cluster Magnetron Sputter System

## Model: SA-VKC500

SA-VKC500 is a production-grade multi-chamber cluster magnetron sputter system. Featuring robust construction, high operational stability and reliability, as well as a highly automated control system, it is capable of meeting mass-production requirements for semiconductor-grade manufacturing.



### Feature

- Independent chambers
- Minimize cross-contamination
- Multi-functional integration
- High process efficiency

### Application

- Laser
- R&D
- Integrated circuit
- MEMS

### Specifications:

| Parameter                   | Descriptions                                                                    |
|-----------------------------|---------------------------------------------------------------------------------|
| Number of Process Chambers  | 5(max.)                                                                         |
| Process Chamber Type        | Sputter & Degas & Pre-clean                                                     |
| Number of Sample Chambers   | 2(max.)                                                                         |
| Autosampling Chamber        | Integrated with BROOKS system                                                   |
| Ion Source                  | DC/RF ion source, optional                                                      |
| Pumping System              | Cryopump / magnetically levitated turbo-molecular pump<br>+ Dry mechanical pump |
| Flow Control                | Digital mass flow meter                                                         |
| Coating Uniformity          | ±2%                                                                             |
| Coating Repeatability       | ±2%                                                                             |
| Uniform Deposition Area     | Ø300 mm(max.)                                                                   |
| Uniform Etching Area        | Ø200 mm(max.)                                                                   |
| Ultimate Vacuum             | 1E-5Pa                                                                          |
| Vacuum Measurement          | Full-range vacuum gauge + Capacitance diaphragm gauge                           |
| Temperature Control Range   | -50~500℃                                                                        |
| Space Requirements(L×W×H,m) | 3.73×2.75×2.2                                                                   |

**Principle:**

